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# 55th Annual Fuze Conference

## Fuzing's Evolving Role in Smart Weapons

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### **Development of a new MEMS High-g Accelerometer**

**R. Külls,**  
S. Nau, S. Heß, N. Pilous  
Fraunhofer Ernst-Mach-Institut EMI

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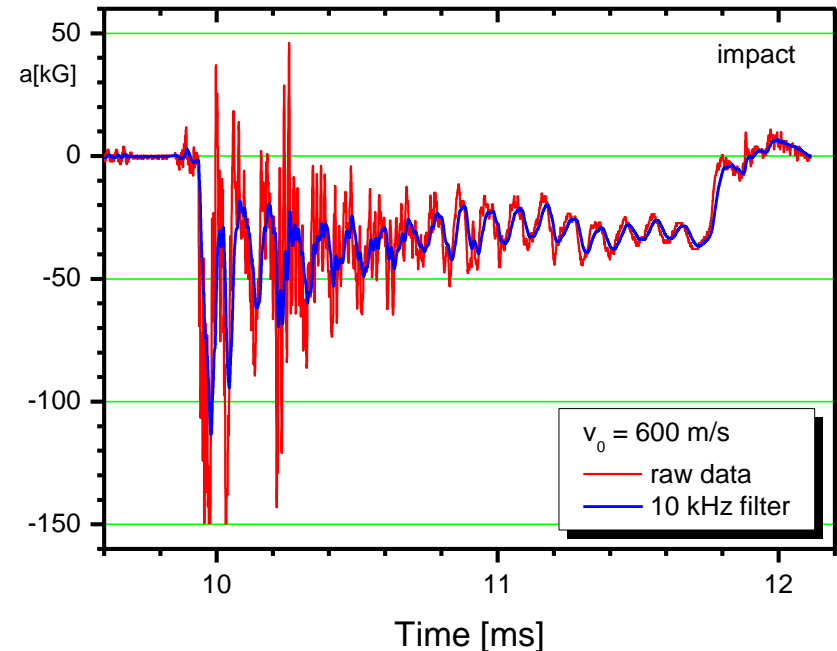
# OUTLINE

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- Introduction
  - High-g Applications
- Theory
  - Transient Excitations
- Design
- First Experimental Data
  - Hopkinson Bar
  - 200,000 g Measurement
- Summary and Outlook

# High-g Applications: Research

- Analysis of highly dynamic processes
  - Shock-testing of electronics  
Measurement range needed:  
50,000 g
  - Material characterization  
g-Range > 80,000 g
  - Penetration processes  
g-Range > 100,000 g
  - Near field blast  
g-Range > 100,000 g



# High-g Applications: Military

Pictures: Wikipedia

- High-g hardened fuzing in smart weapons
  - Large warheads
  - Artillery shells
  - Upcoming:  
Smaller calibers  
> 100,000 g
- The smaller the ammunition, the bigger the acceleration

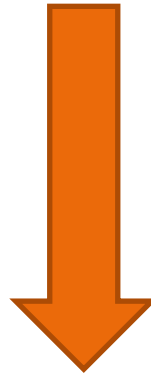


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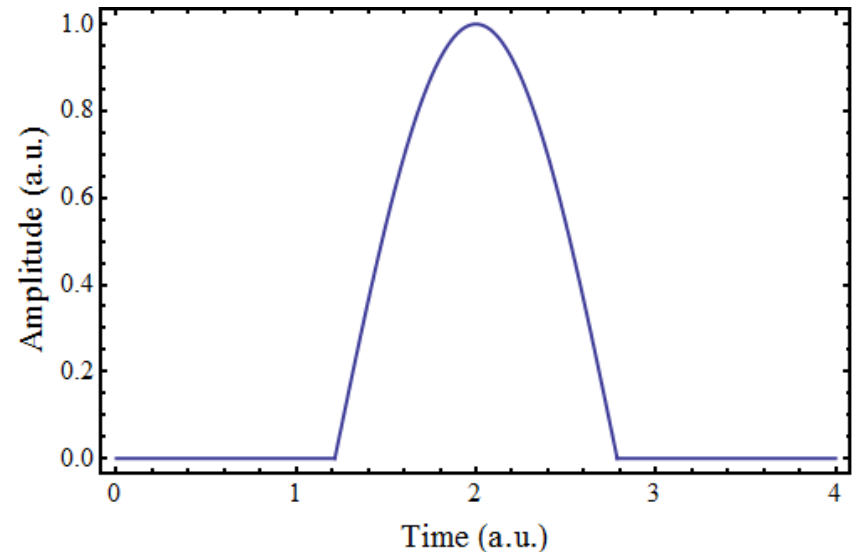
Requirements:  
g-Range  
Survivability  
Size

- The smaller the ammunition, the bigger the acceleration
- Need for small, affordable (very-)high-g accelerometer

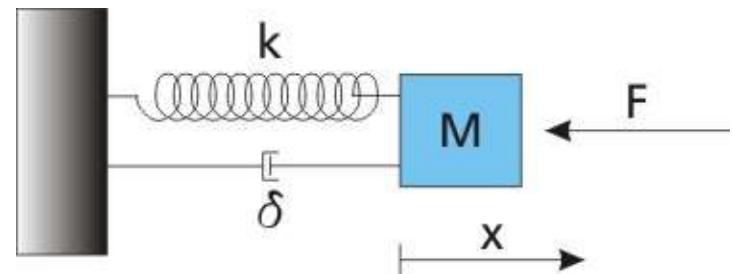


# Basics of High-g Accelerometry

- Shock pulse:
  - “short“, “discontinuous“, “rapidly varying“

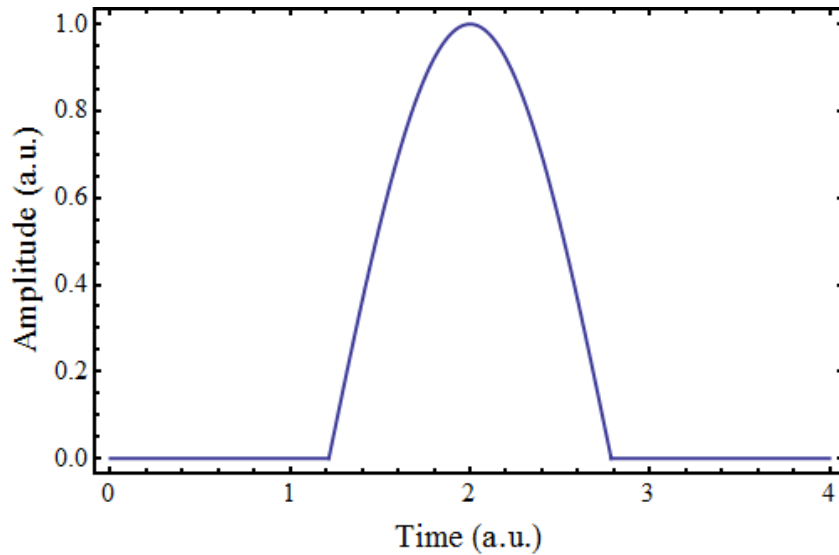


- Accelerometer:
  - Spring-mass-system with resonant frequency
  - Displacement results in signal

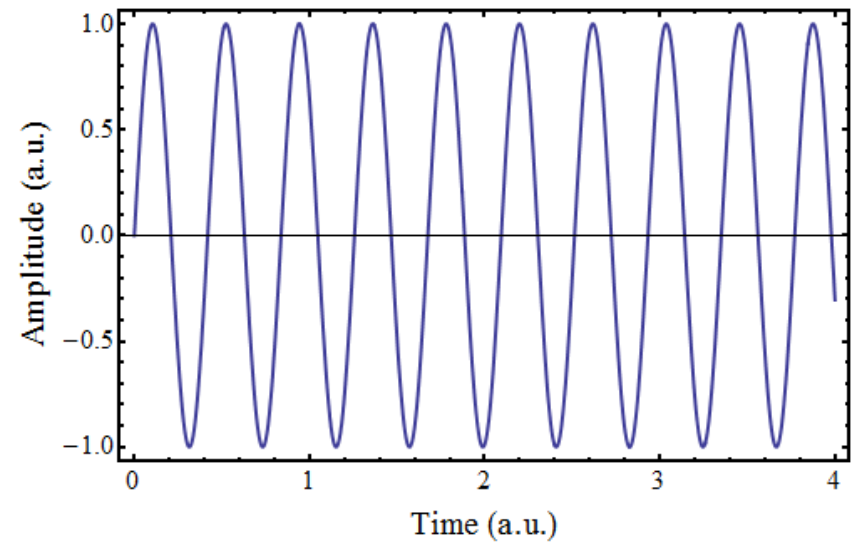


# Excitation of a Spring-Mass-System: Sample Pulse

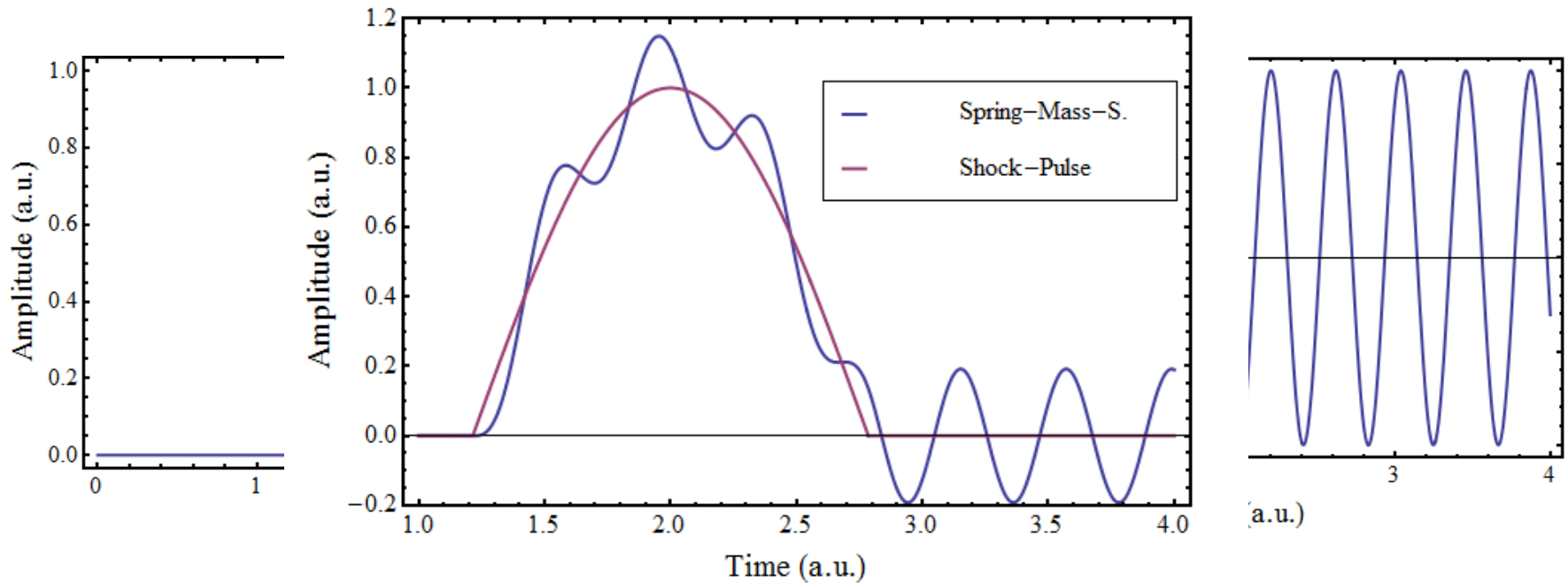
Shock-Pulse



Spring-Mass-System



# Excitation of a Spring-Mass-System: Analytical Solution

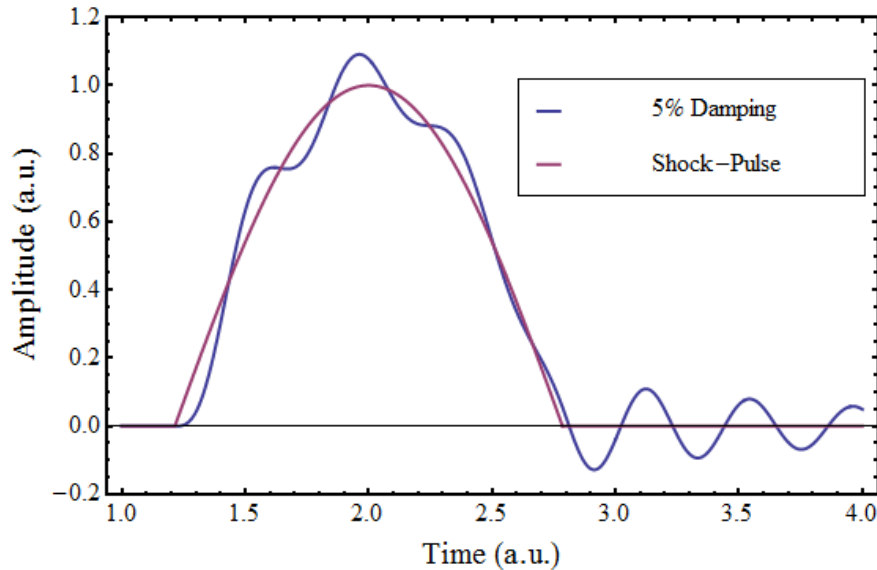


## ■ How to avoid oscillations and over-excitation?

1. Damping (+ stops)
2. Higher resonant frequency

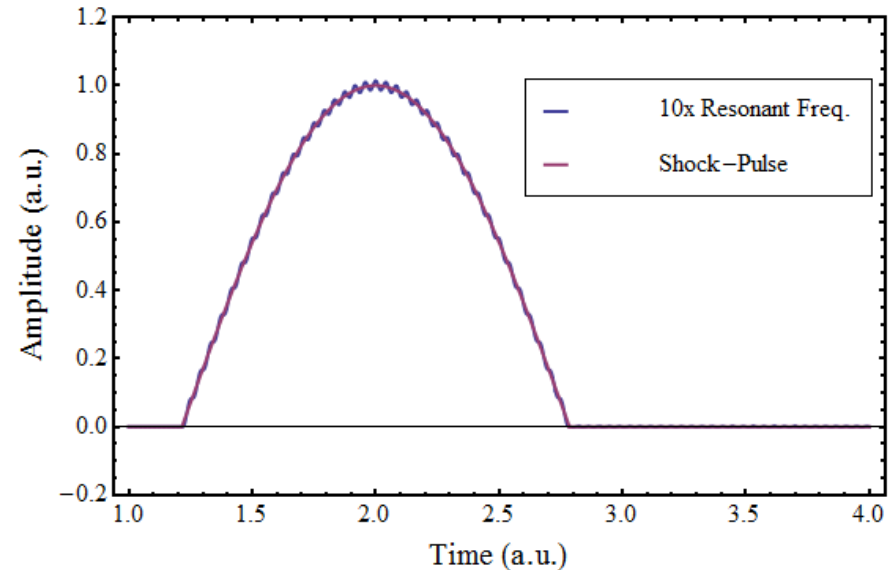


# Reducing Oscillations



## ■ 5% Damping:

- Over-excitation 15% -> 10%
- Oscillations 20% -> 10% -> 0%

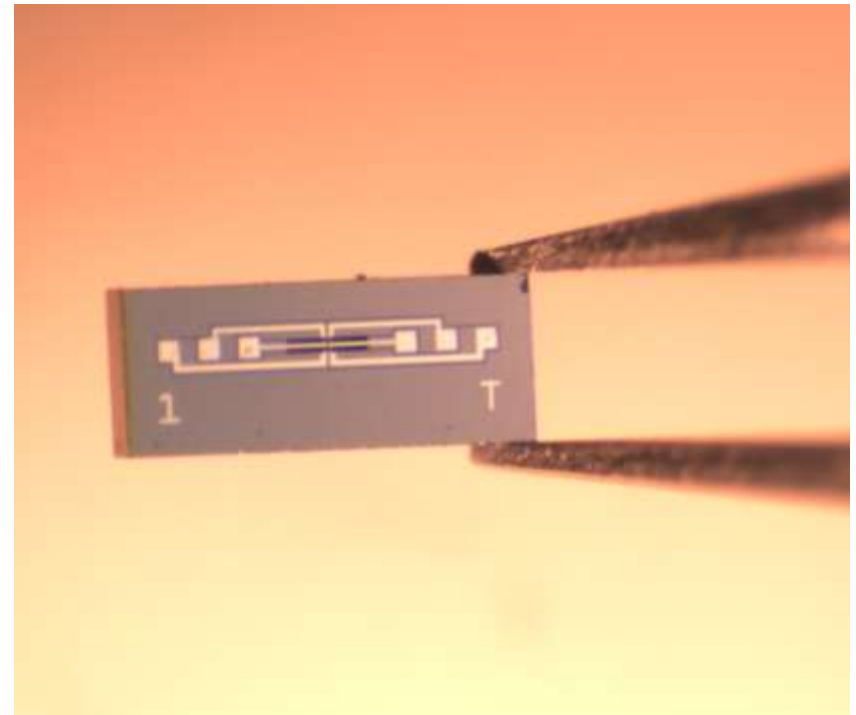


## ■ 10x Resonant Frequency:

- Over-excitation 15% -> 2%
- Oscillations 20% -> 2%

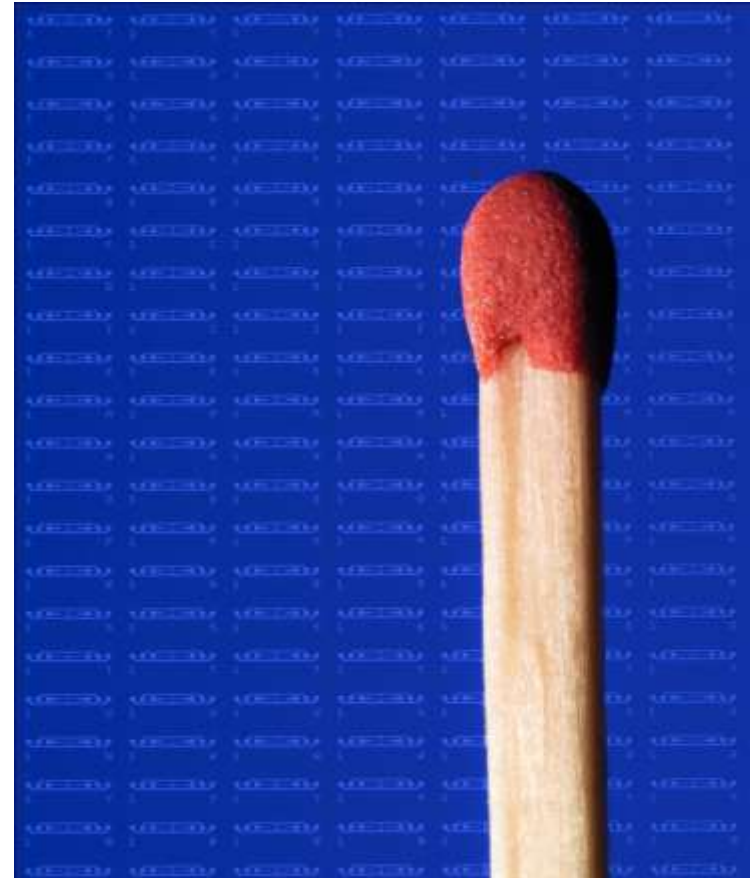
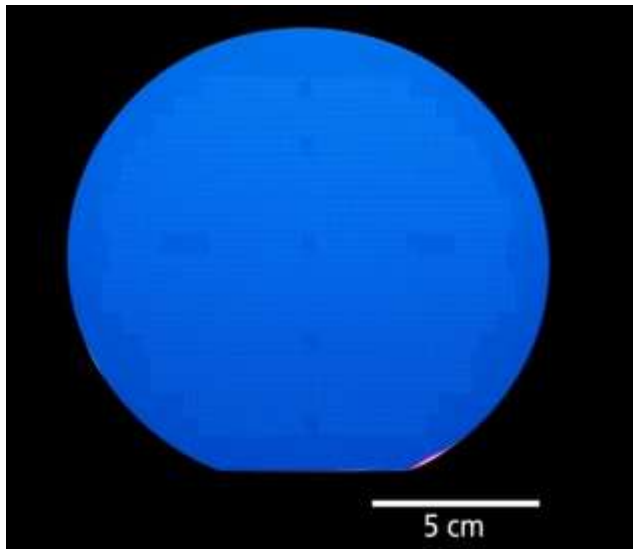
# EMI Accelerometer

- Undamped, piezoresistive, MEMS accelerometer
- Status of development
  - Design is patent pending
  - First specimens were successfully manufactured and tested
- Different variants exist:
  - Measurement range  $> 100,000 \text{ g}$
  - Resonant frequency  $1 - 3 \text{ MHz}$
  - Sensitivity  $0.1 - 1 \mu\text{V}/V_{\text{exc}}/\text{g}$



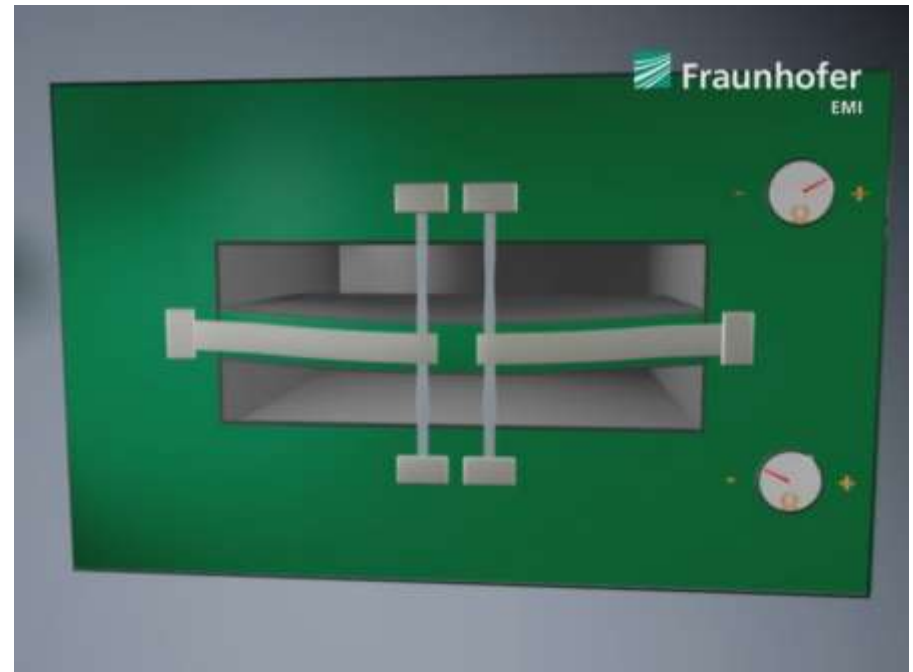
# EMI Accelerometer

- Manufactured with standard silicon processes, single sided
- Sensor-chip about 2 x 1 mm<sup>2</sup>
- Straightforward integration of 2D and 3D measurement capabilities



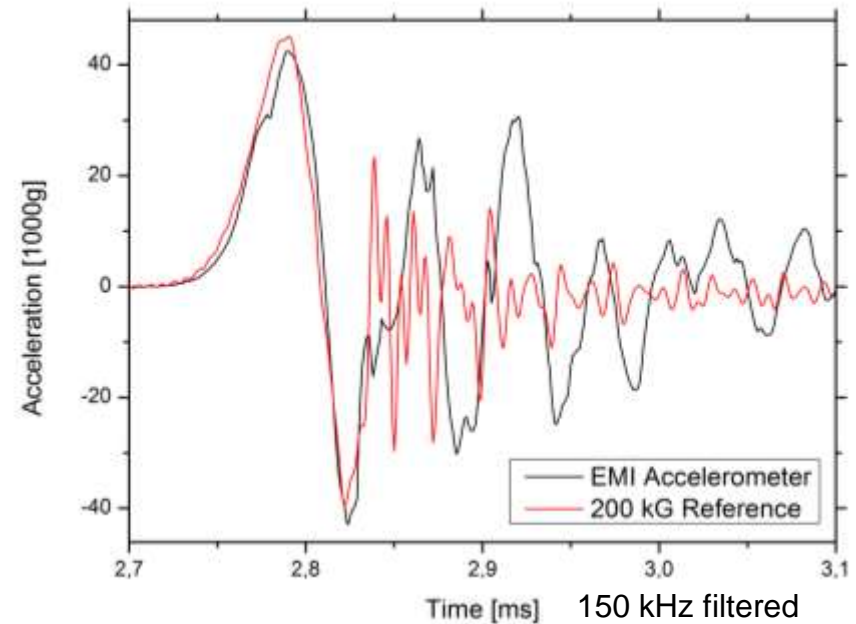
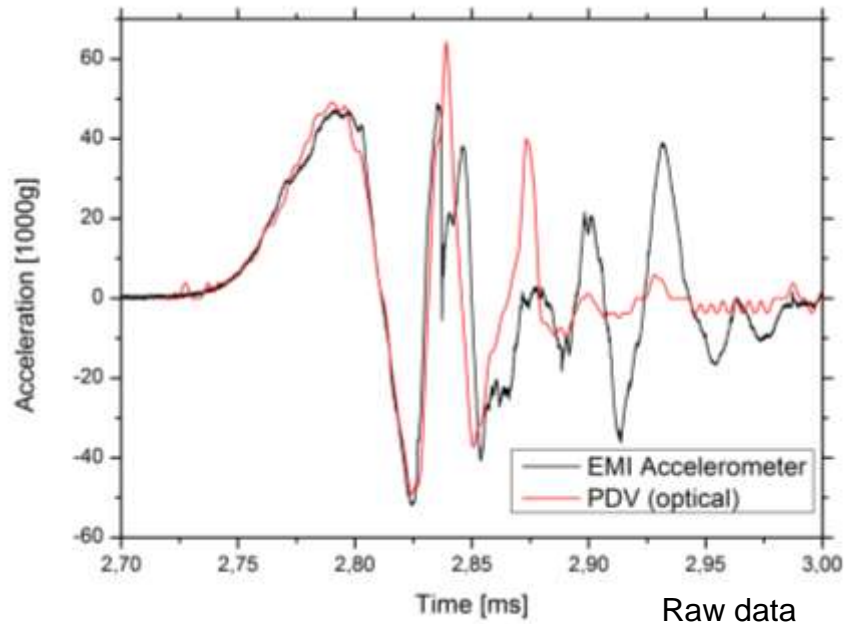
# EMI Accelerometer: Functional Principle

- Main components:
  - Flexural plate
  - Self-supporting piezoresistive elements
  - Full Wheatstone-bridge
- Functional principle:
  - Inertial forces cause deflection of plate
  - Straining of piezoresistive elements
  - Change in resistance is measurement signal

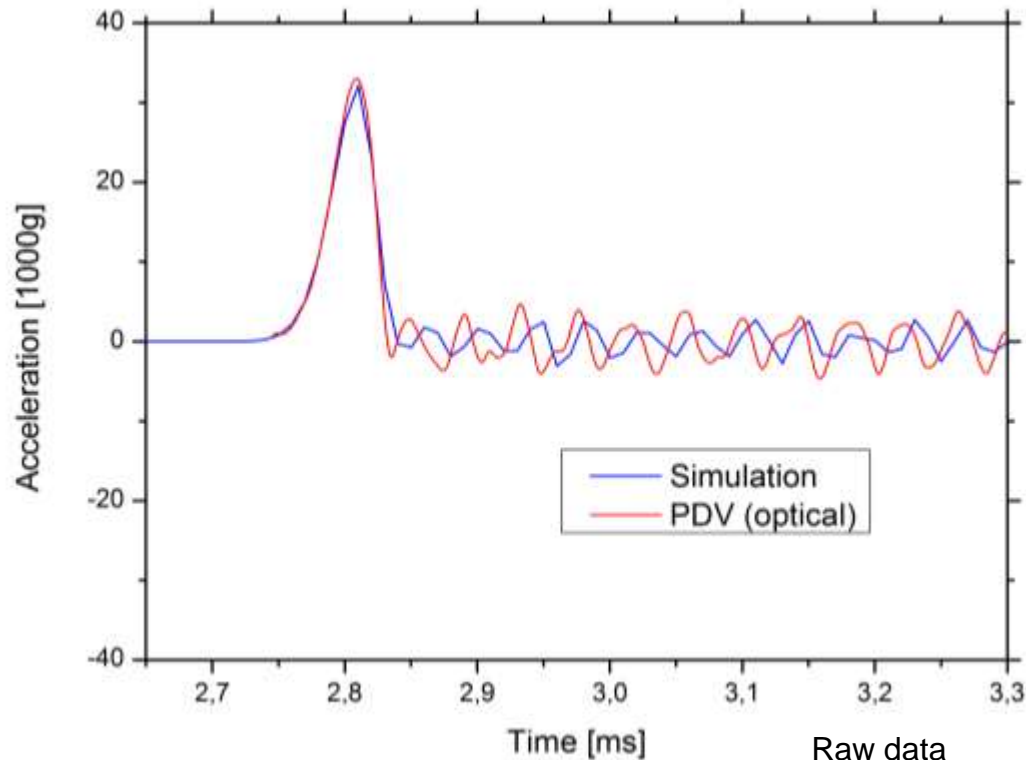


# Hopkinson Bar Measurements

- Assessment of accelerometer performance on Hopkinson bar
- Comparison:
  - First peak well reproduced
  - Differences after breakaway

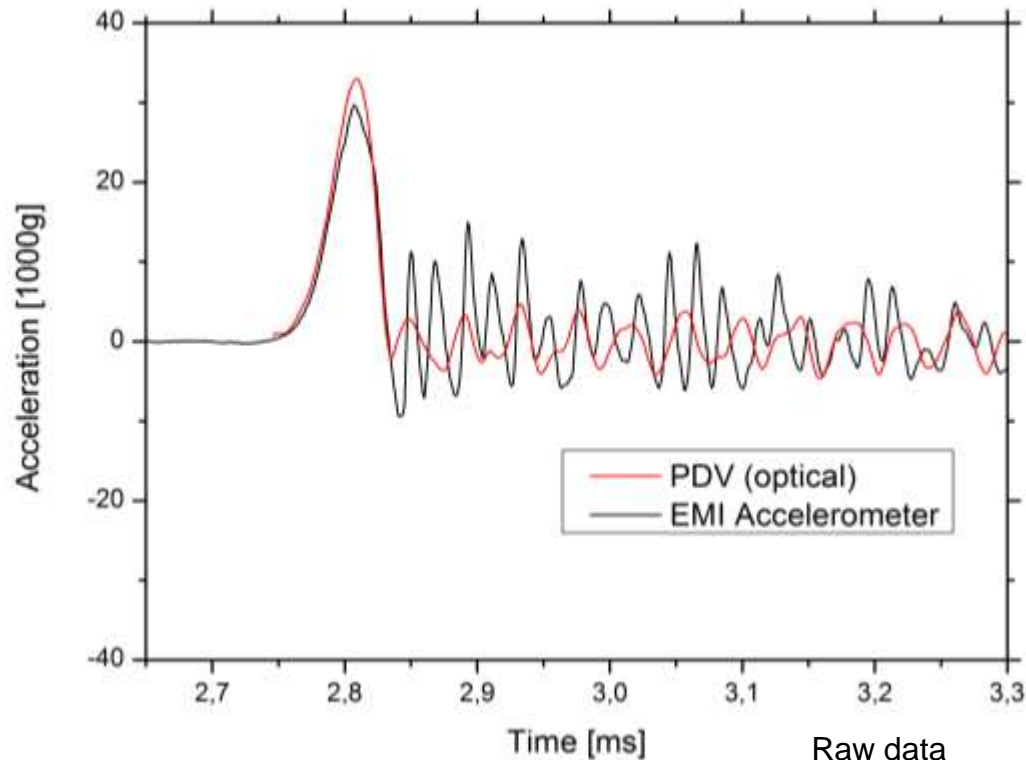


# Shock Plate Test: Reference



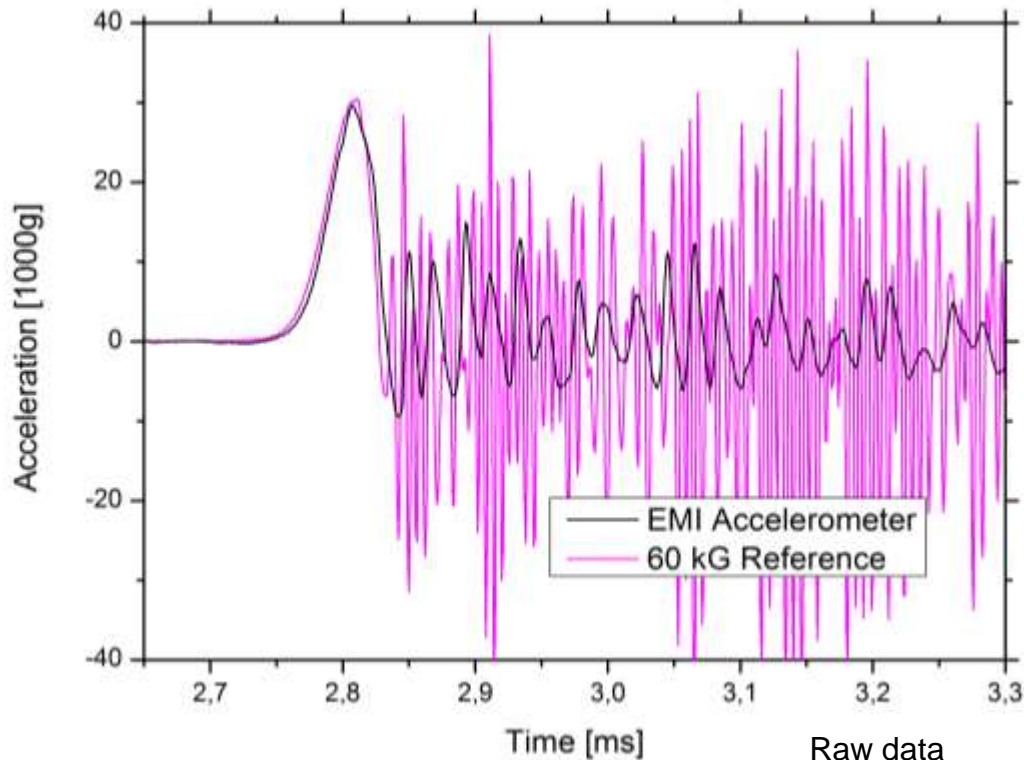
- Test of accelerometers on shock plate
- Simulation and reference measurement with PDV
  - 30,000 g pulse
  - Plate shows oscillations with 23 and 46 kHz (1<sup>st</sup> and 2<sup>nd</sup> harmonic)

# Shock Plate Test: Comparison



- Second flyer plate experiment with EMI accelerometer and 60 kG lightly damped sensor
- 2<sup>nd</sup> harmonic more distinct in this test

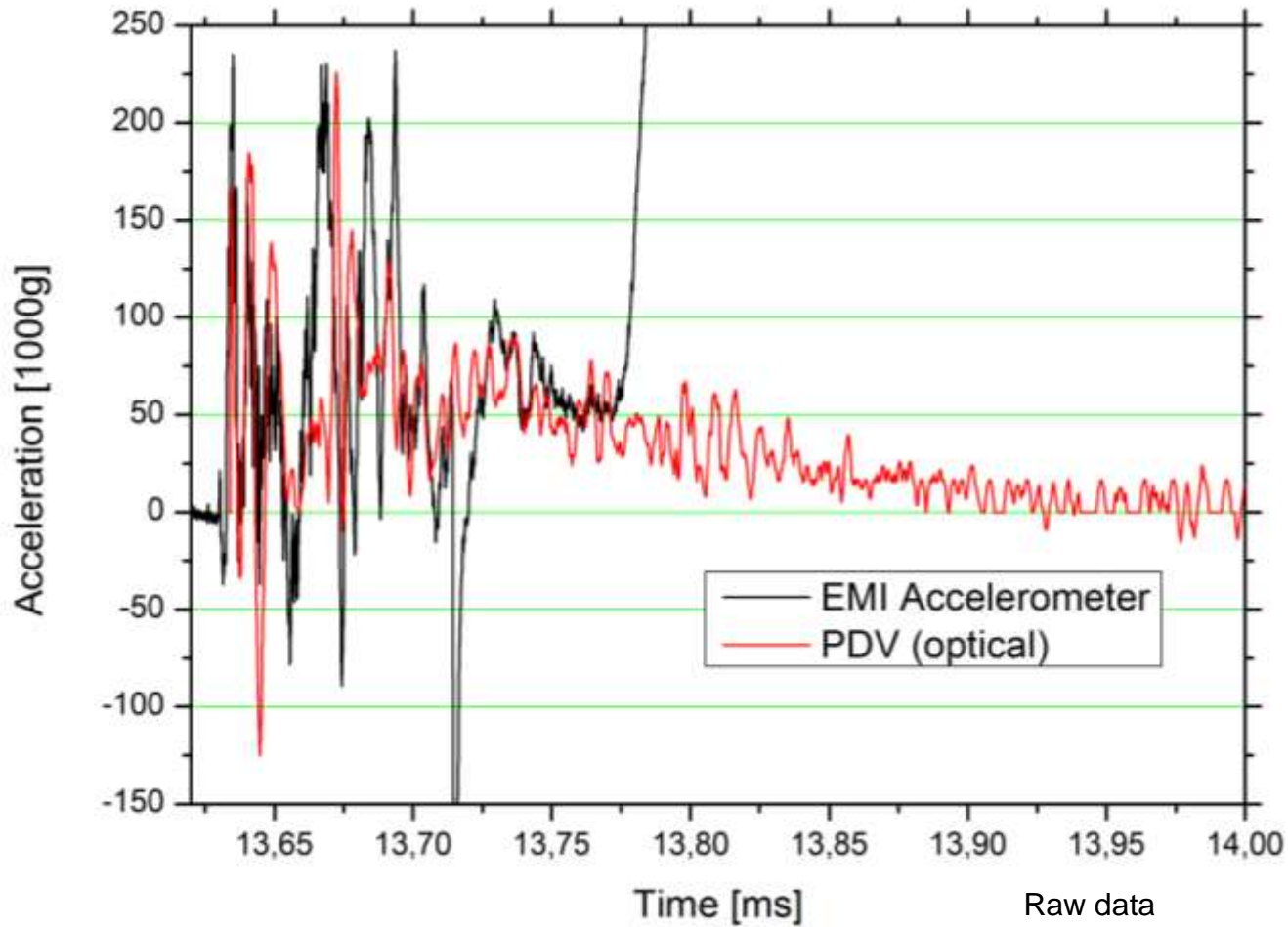
# Flyer Plate Test: Comparison



- Second flyer plate experiment with EMI accelerometer and 60 kG lightly damped MEMS
- 2<sup>nd</sup> harmonic more distinct in this test
- Both sensors reproduce first peak
- EMI: Plate oscillations with 23 and 46 kHz are well visible
- 60 kG: 165 kHz resonant frequency overlays plate dynamics

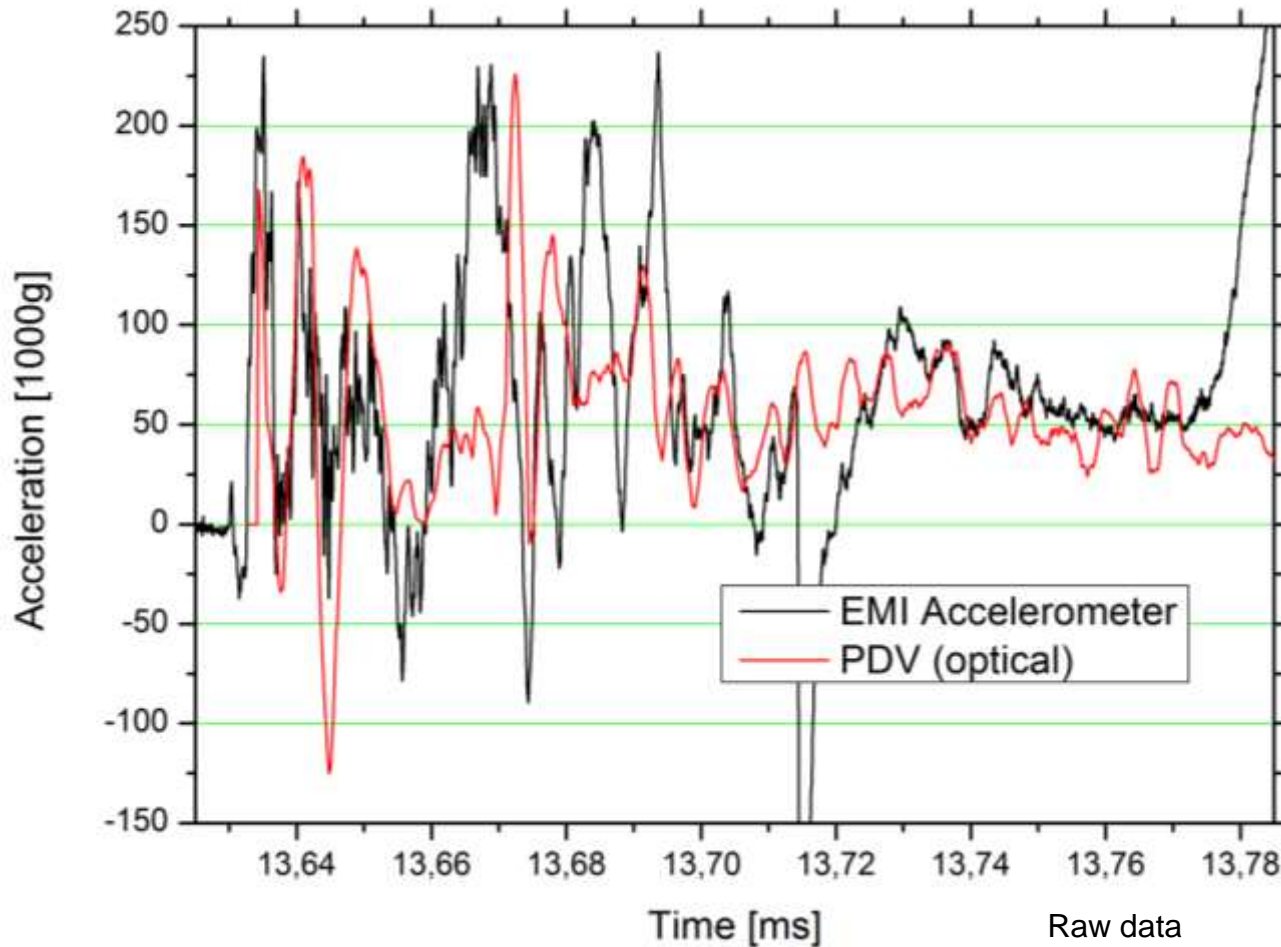


# 200,000 g Measurement



- Impact experiment with PDV measurement
- Overall agreement is good
- Failure of cable connection

# 200,000 g Measurement



- Confirmed acceleration over 200,000 g
- Defective contact at 13.72 ms and failure of cable at 13.78 ms
- No resonant oscillation
- Sensor-chip is completely intact!

# Summary

- EMI accelerometer has been designed and manufactured
  - Design patent pending
  - Standard silicon processes
  - Successful proof of concept
  
- The EMI design combines:
  - ... the sensitivity of medium g-range sensors (  $> 0.2 \mu\text{V}/V_{\text{exc}}/\text{g}$ ) (proven)
  - ... with the survivability of high g-range sensors (  $> 200.000 \text{ g}$ ) (proven)
  - ... while having a uniquely high bandwidth (  $> 2 \text{ MHz}$ ) (not meas. yet)

# Outlook

- Determination of accelerometer performance is to be completed
  
- Further development will focus on:
  1. Realization of an “easy to use” and robust package
  2. Monolithical integration of bi- or tri-axial accelerometers

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# Thank you for your Attention!

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## Further Information:

Robert Külls  
Fraunhofer EMI  
Am Klingelberg 1  
79588 Efringen-Kirchen / Germany  
Tel.: +49 7628 / 9050 – 736  
E-mail: robert.kuells@emi.fhg.de

Dr. Siegfried Nau  
Fraunhofer EMI  
Am Klingelberg 1  
79588 Efringen-Kirchen / Germany  
Tel.: +49 7628 / 9050 – 685  
E-mail: siegfried.nau@emi.fhg.de